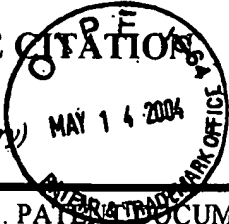


Form PTO-1449				Attorney Docket No. 220101-1011		Serial No. 10/772,740		
<b>INFORMATION DISCLOSURE CITATION</b> <i>(Use several sheets if necessary)</i>				Applicant Yonhua Tzeng				
				Filing Date February 5, 2004		Group 1762		
 <b>U.S. PATENT DOCUMENTS</b>								
Examiner Initials	Item	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
EF	A	6,284,315	9/4/01	Tzeng	427	249.1	1/14/00	
<b>FOREIGN PATENT DOCUMENTS</b>								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)</b>								
EF	B	Tzeng, et al.; Effects of oxygen and hydrogen on electron field emission from microwave plasma chemically vapor deposited microcrystalline diamond, nanocrystalline diamond, and glassy carbon coatings						
<p>* EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.</p>								
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